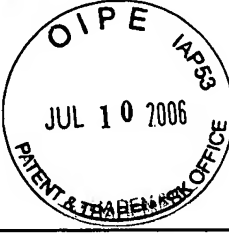


<p style="text-align: center;">IN THE UNITED STATES PATENT AND TRADEMARK OFFICE</p> 	<i>Application No.</i>	10/046,753
	<i>Filing Date</i>	January 17, 2002
	<i>First Named Inventor</i>	Koji Okamoto
	<i>Group Art Unit</i>	3627
	<i>Examiner Name</i>	Steven B. McAllister
	<i>Confirmation No.</i>	2640
	<i>Attny. Dkt. No.</i>	2922-181
<p><i>Title of the Invention: SUPPLY SYSTEM OF COMPOUND FOR CHEMICAL VAPOR DEPOSITION AND THIN-FILM MANUFACTURING SYSTEM HAVING THE SAME COMPOUND SUPPLY SYSTEM</i></p>		

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

In response to the Office Action mailed February 10, 2006, please enter the amendments and remarks contained on the following pages, which are summarized below. Applicant requests a two-month extension of time, which extends the original due date of May 10, 2006 to July 10, 2006.

Amendments to the Claims are reflected in the listing of claims which begin on page 2 of this paper.

Amendments to the Drawings begin on page 6 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 7 of this paper.

An **Appendix** including amended drawings figures is attached following page 9 of this paper.